

Microfabricated Ion Traps for Quantum Simulations

Bjoern Lekitsch
IQT Group, University of Sussex

US

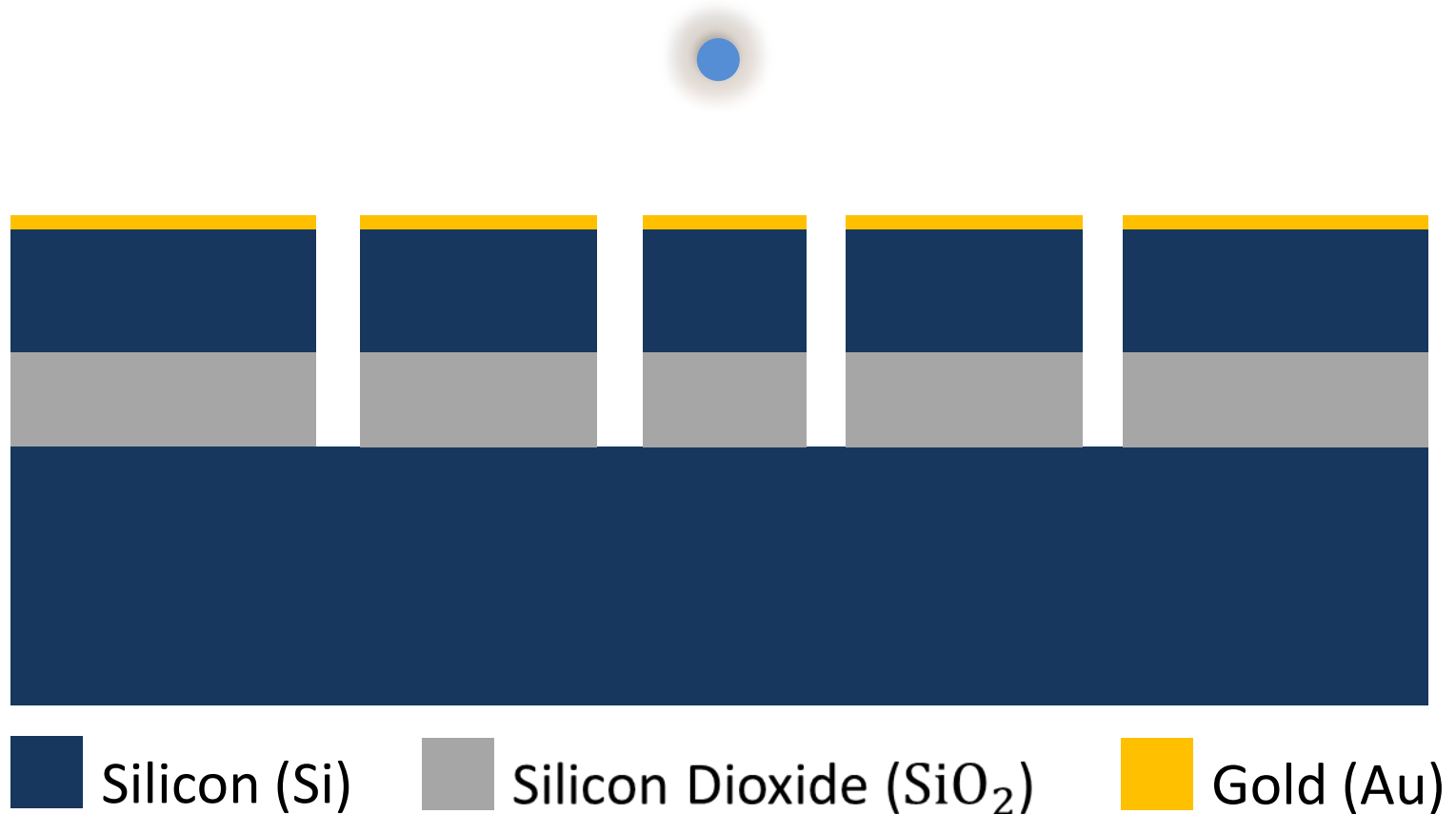
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Ion Quantum Technology Group

Two-Dimensional Ion Trap Array

- ▶ Simple Fabrication Process
- ▶ Extremely High Breakdown Voltage
- ▶ 2D Lattice Ion Trap
- ▶ Site to Site Shuttling

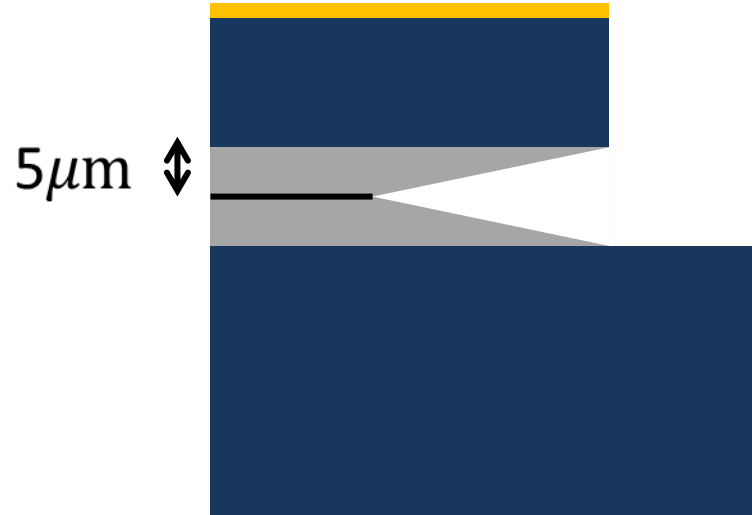
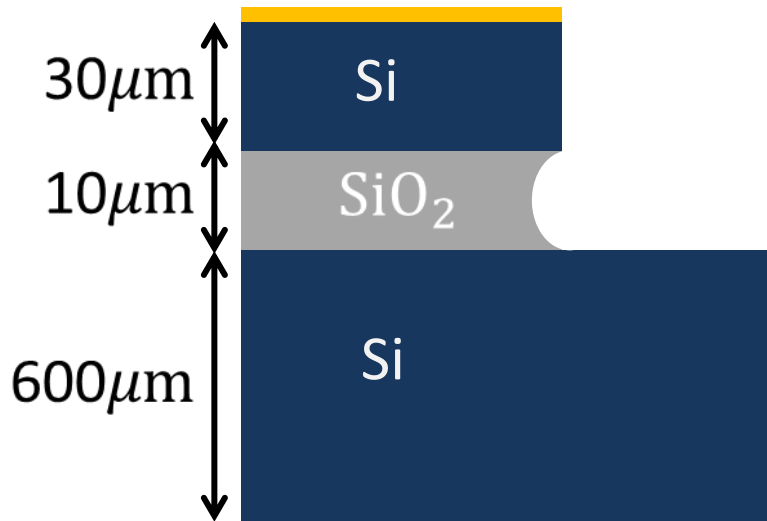
Two-Dimensional Ion Trap Array

▶ Simple Fabrication Process

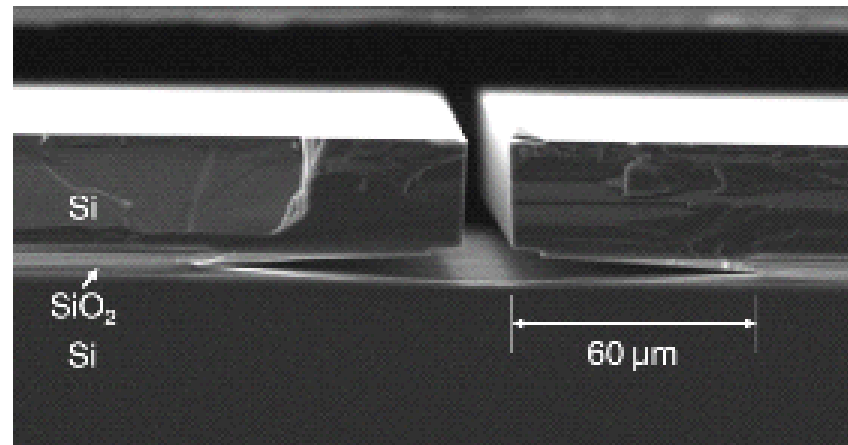


Two-Dimensional Ion Trap Array

- ▶ Extremely High Breakdown Voltage

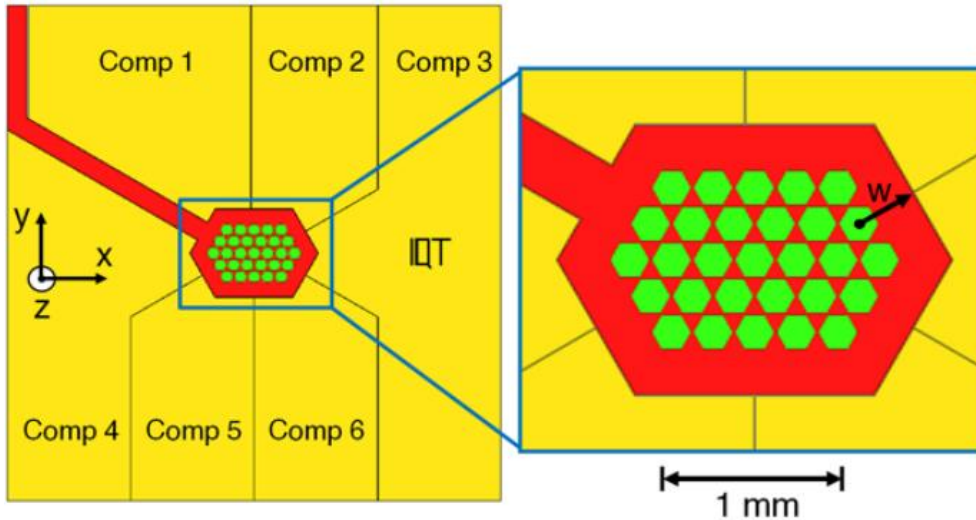


$$V_{\text{DC}} = 1298 \text{ V}$$
$$V_{\text{RF}} = 1061 \text{ V}$$



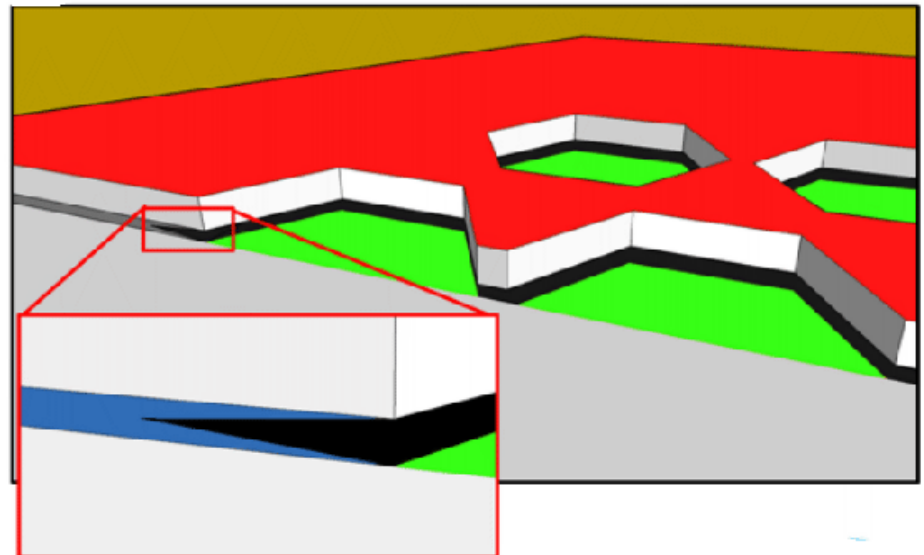
Two-Dimensional Ion Trap Array

► 2D Lattice Ion Trap



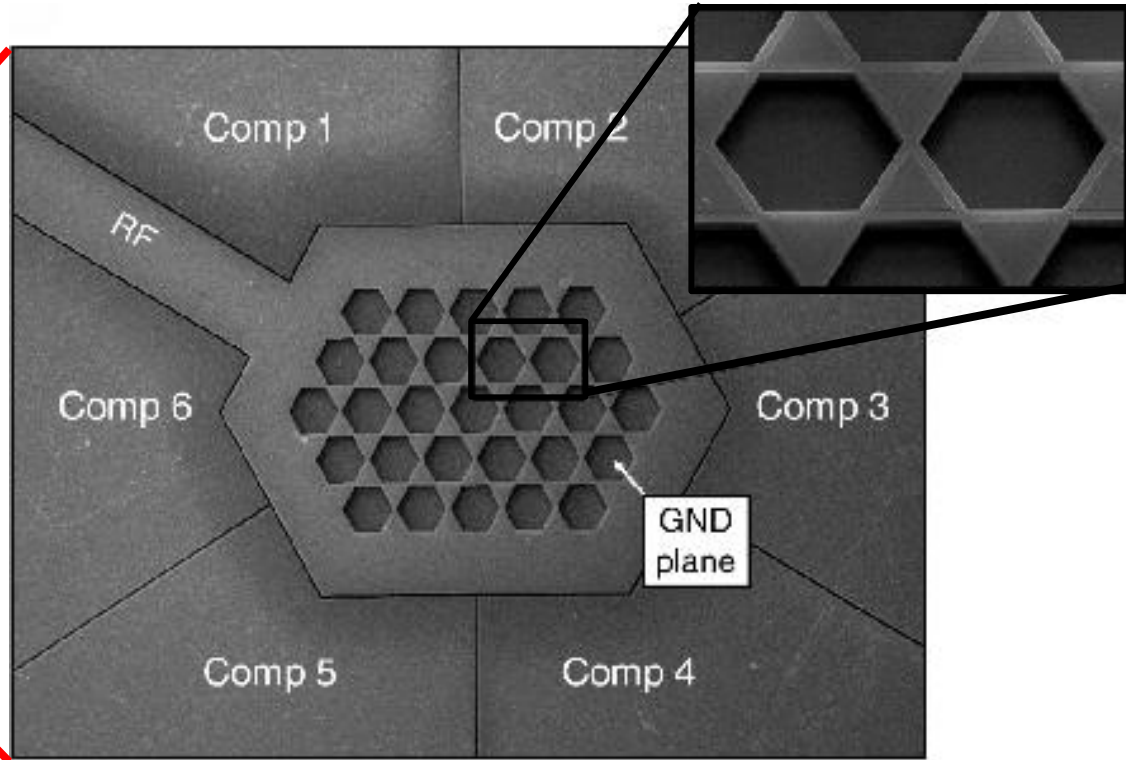
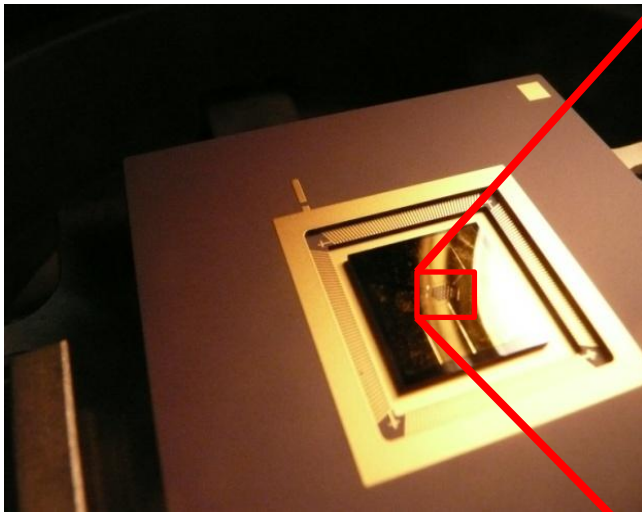
- Hexagon lattice with 6 nearest neighbours
- $270.5\mu\text{m}$ separation
- Scalable concept

- $156\mu\text{m}$ ion-electrode distance
- $60\mu\text{m}$ undercut



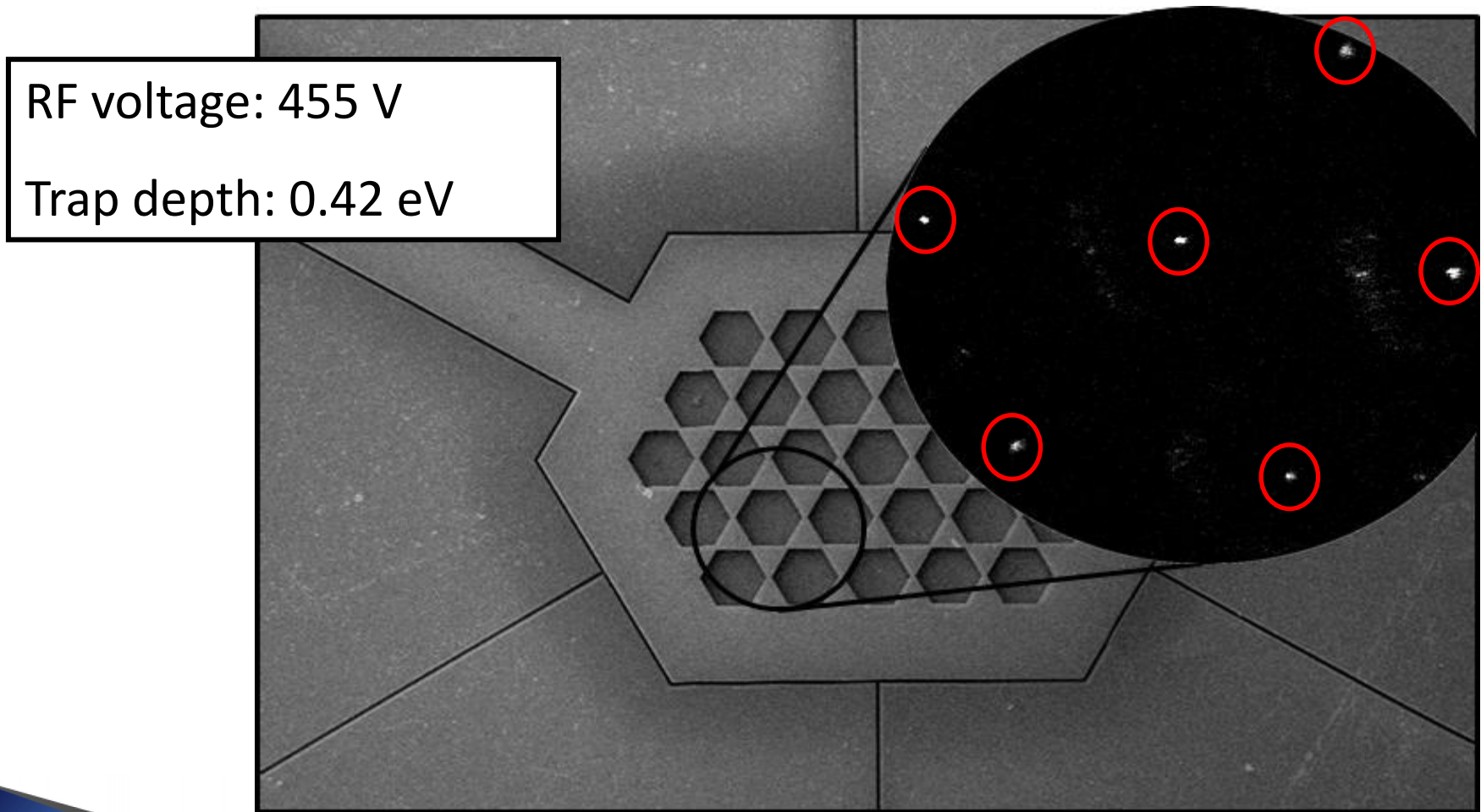
Two-Dimensional Ion Trap Array

► 2D Lattice Ion Trap



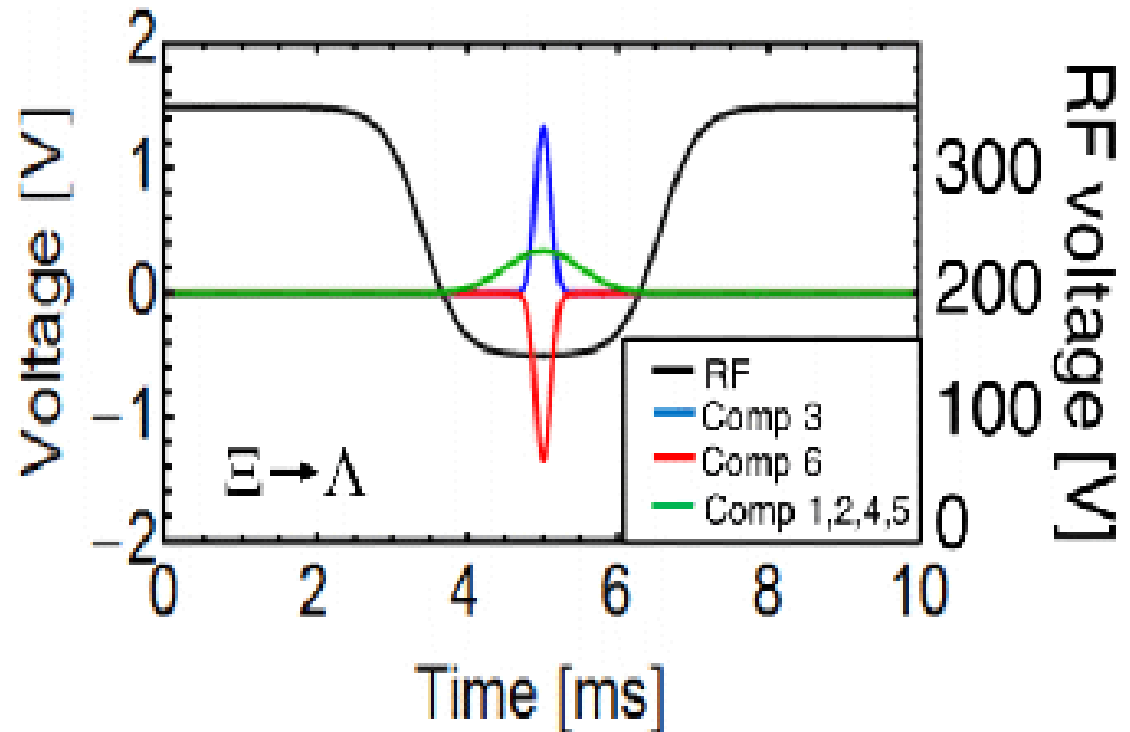
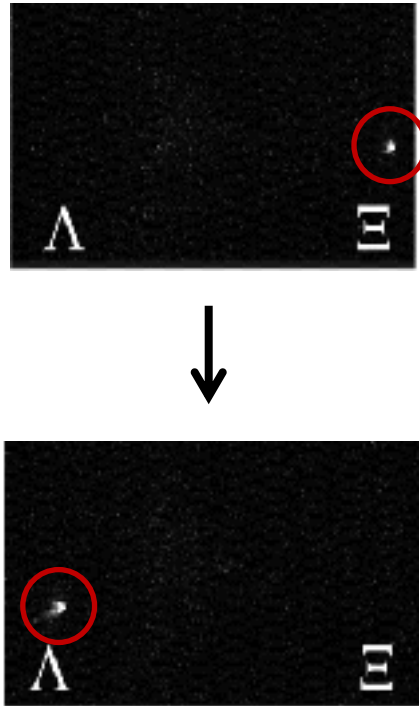
Two-Dimensional Ion Trap Array

► 2D Lattice Ion Trap



Two-Dimensional Ion Trap Array

► Site to Site Shuttling

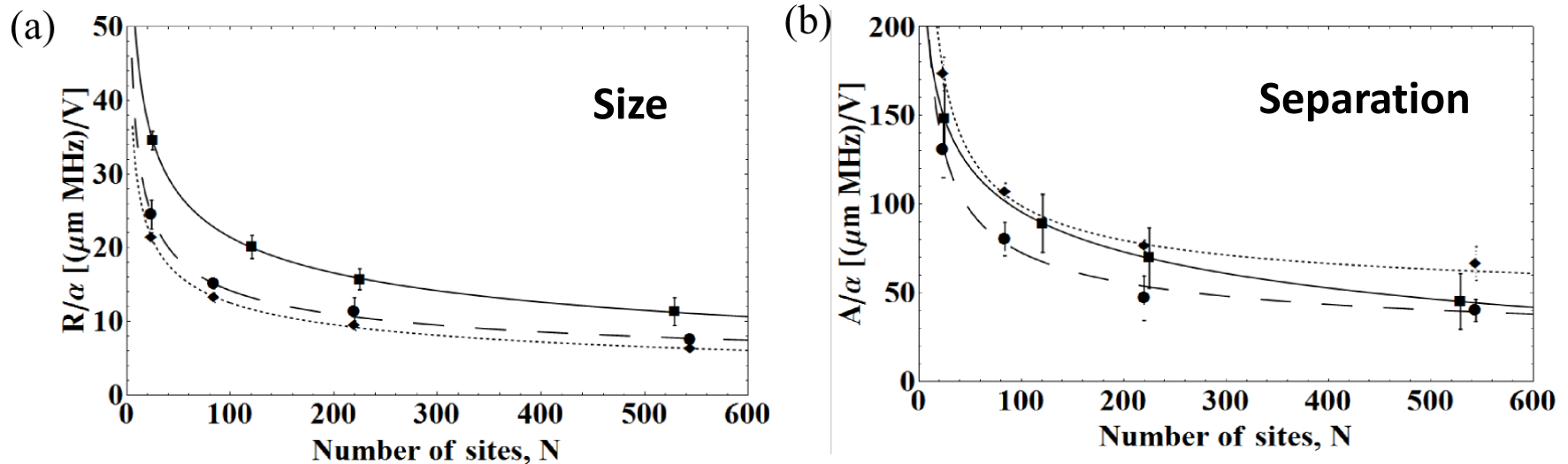


Optimization of Two Dimensional Ion Trap Arrays for Quantum Simulation

- ▶ Polygon Size and Separation
- ▶ Optimum Geometry $^{171}\text{Yb}^+$ Ions
- ▶ Fabrication Mask for Optimal Trap Design

Optimization of Two Dimensional Ion Trap Arrays for Quantum Simulation

► Polygon Size and Separation



$$\alpha = V/\Omega$$

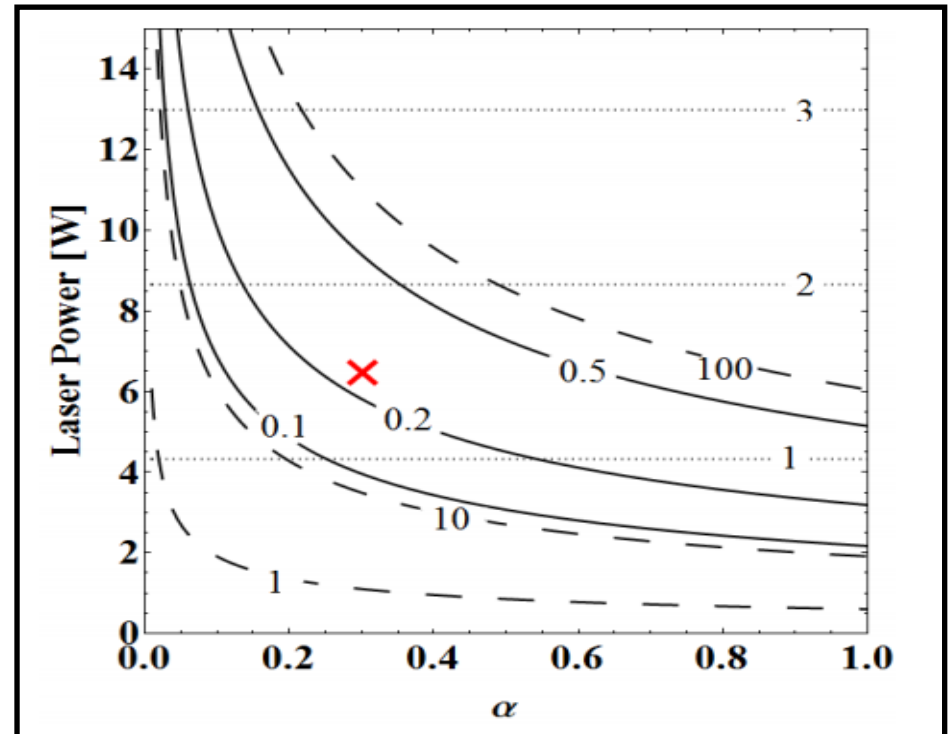
V = RF amplitude, Ω = RF Frequency

Lattice site radius and separation optimized highest interaction in square (squares), hexagonal (circles) and centre rectangular (diamonds) unit cell lattices and $^{171}\text{Yb}^+$ ions.

Optimization of Two Dimensional Ion Trap Arrays for Quantum Simulation

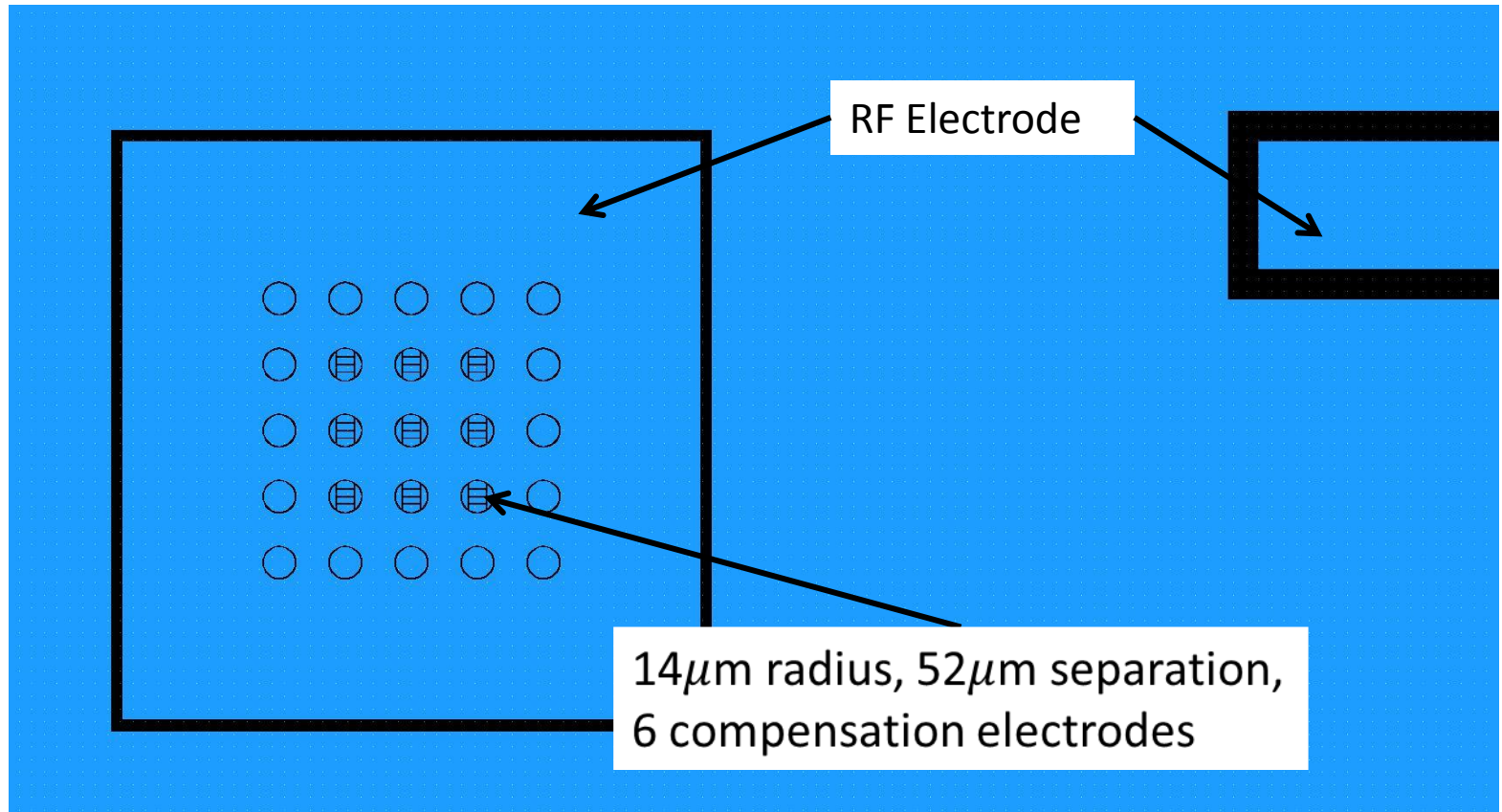
► Optimum Geometry $^{171}\text{Yb}^+$ Ions

- $30\mu\text{m}$ ion height
- 3×3 square unit cell ion trap array
- $14\mu\text{m}$ polygon radius
- $52\mu\text{m}$ separation



Optimization of Two Dimensional Ion Trap Arrays for Quantum Simulation

► Fabrication Mask for Optimal Trap Design

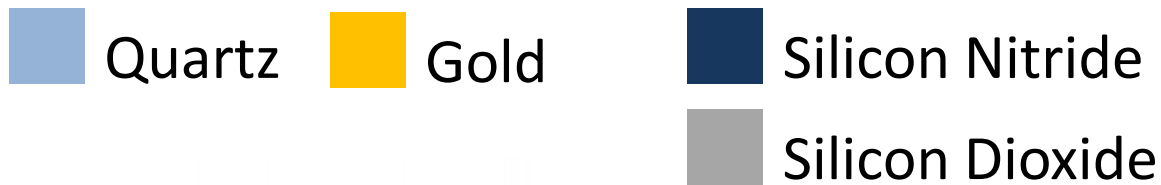
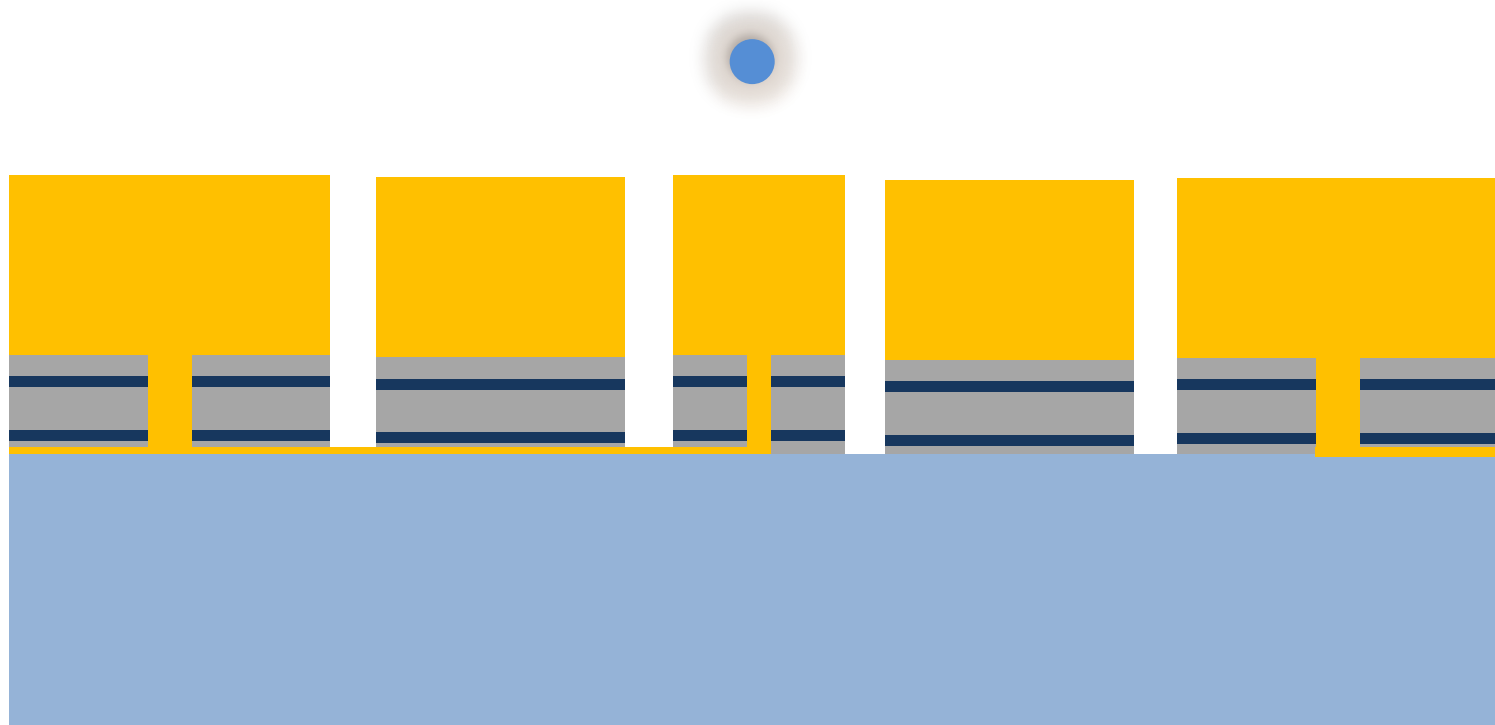


Advanced Microfabricated Ion Traps

- ▶ Multilayer Design with Buried Wires
- ▶ Isolated DC and RF Electrodes
- ▶ Ring Trap
- ▶ Y-Junction with Centre Segmented Electrodes
- ▶ Voltage Control System

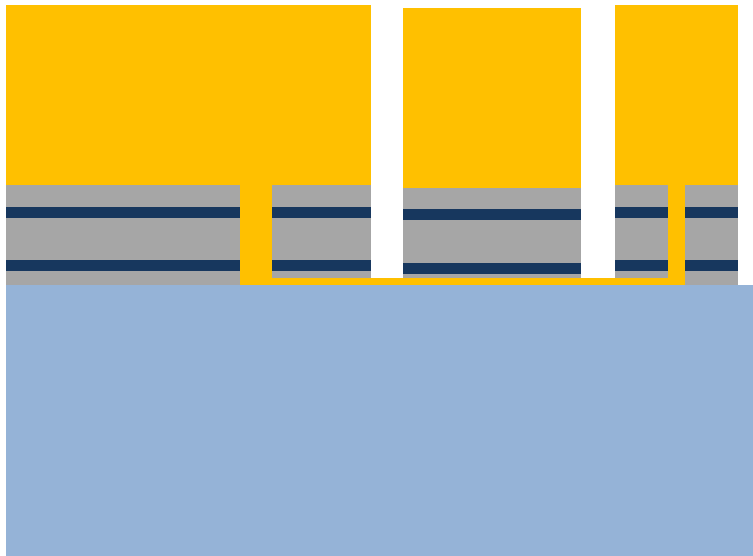
Advanced Microfabricated Ion Traps

► Multilayer Design with Buried Wires

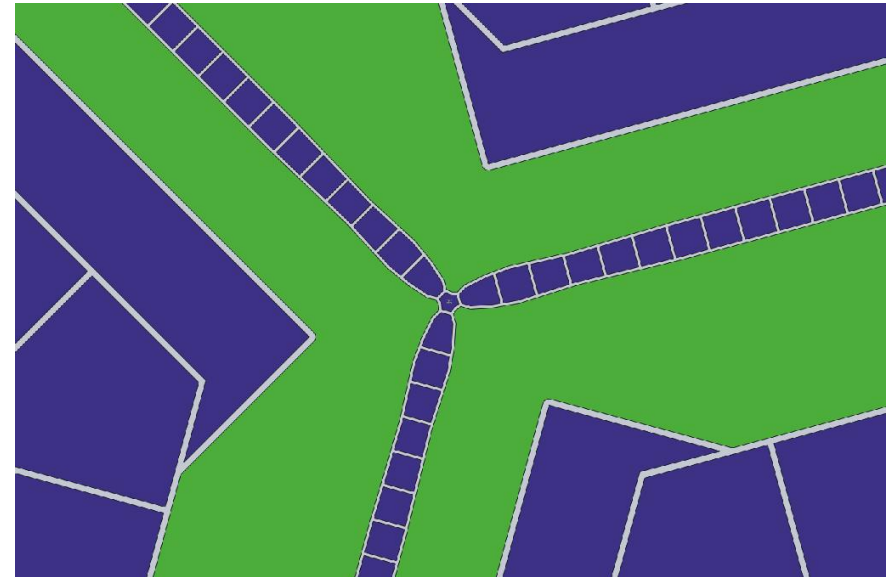


Advanced Microfabricated Ion Traps

▶ Isolated DC and RF Electrodes



Buried wires and vertical interconnect access (VIA) structures

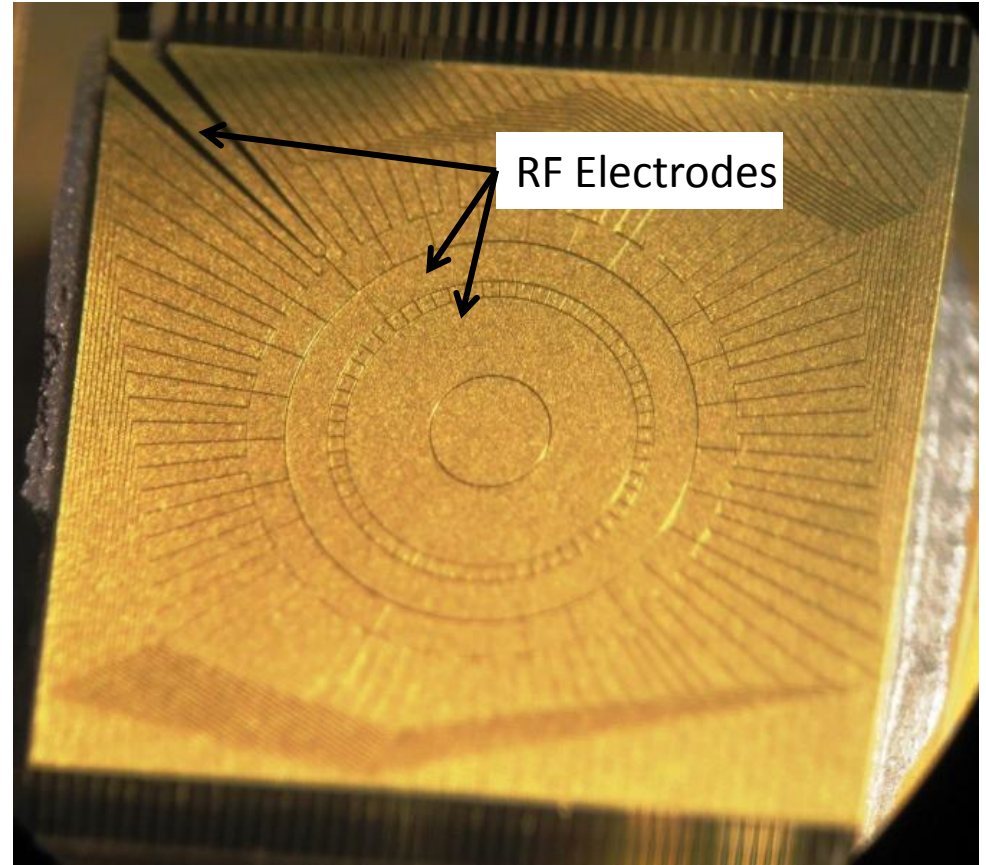


More advanced trap designs with isolated electrodes

Advanced Microfabricated Ion Traps

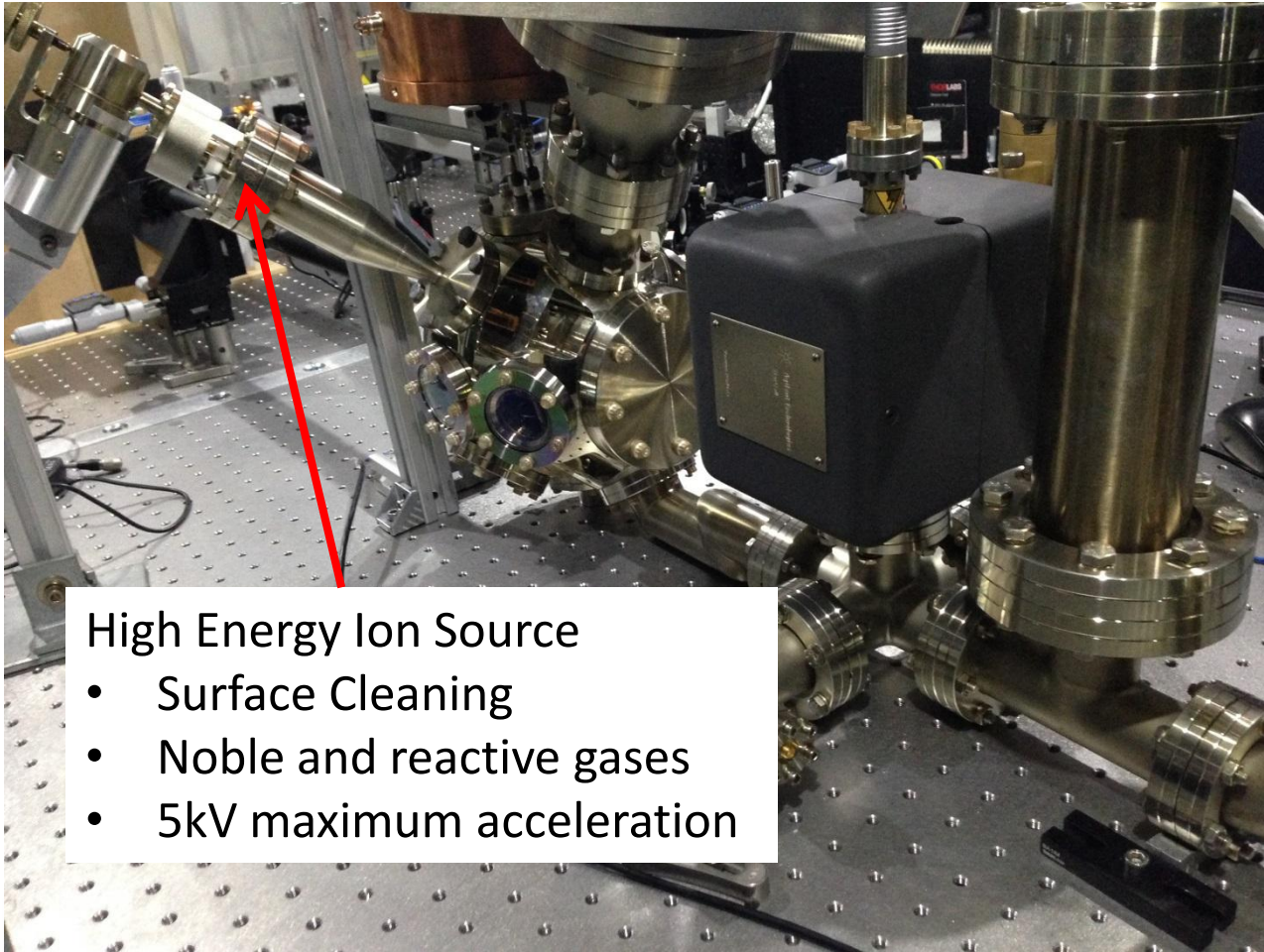
▶ Ring Trap

- Homogenous ion-ion spacing
- $1690\mu\text{m}$ radius
- $245\mu\text{m}$ ion-electrode distance
- Periodic Boundary Conditions
- Variety of experiments possible including Homogenous Kibble-Zurek-mechanism, Hawking radiation, space time crystals, superposition of quantum phase



Advanced Microfabricated Ion Traps

► Ring Trap



High Energy Ion Source

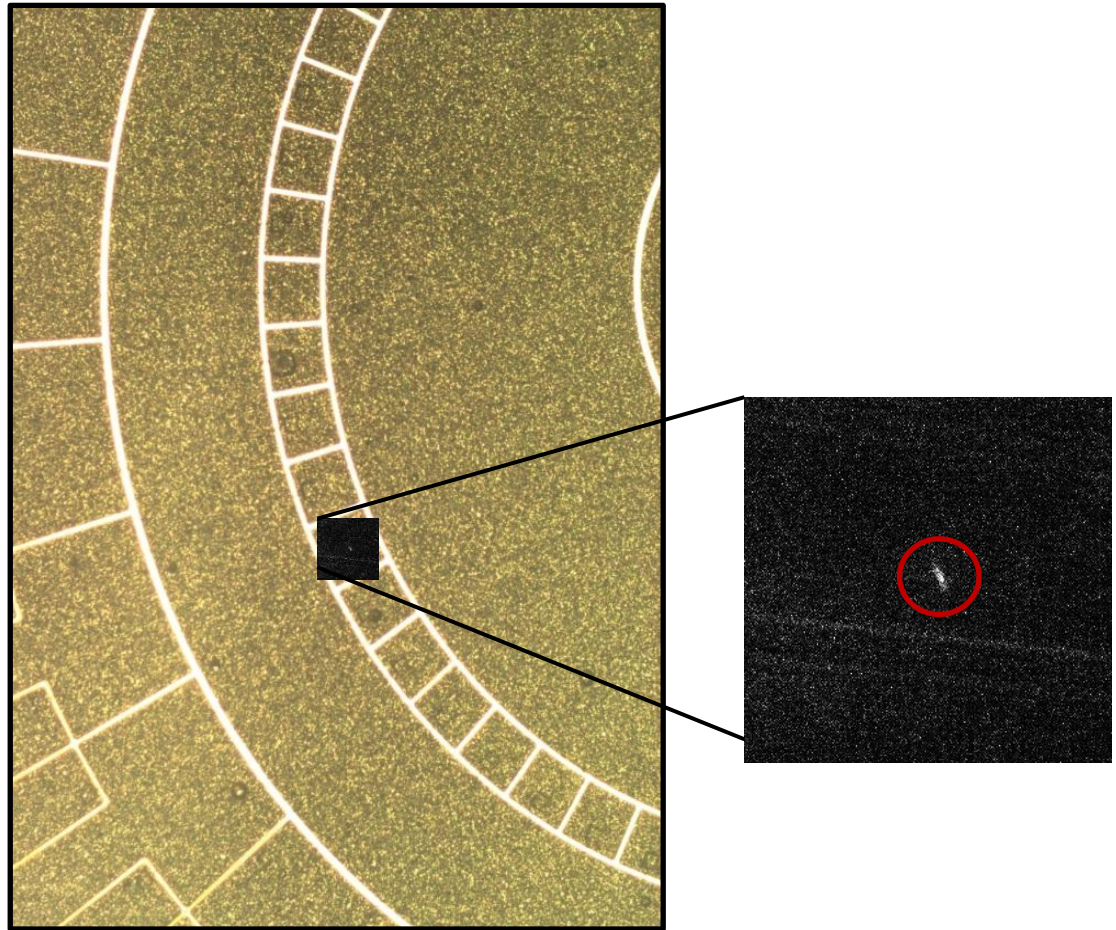
- Surface Cleaning
- Noble and reactive gases
- 5kV maximum acceleration

Advanced Microfabricated Ion Traps

▶ Ring Trap

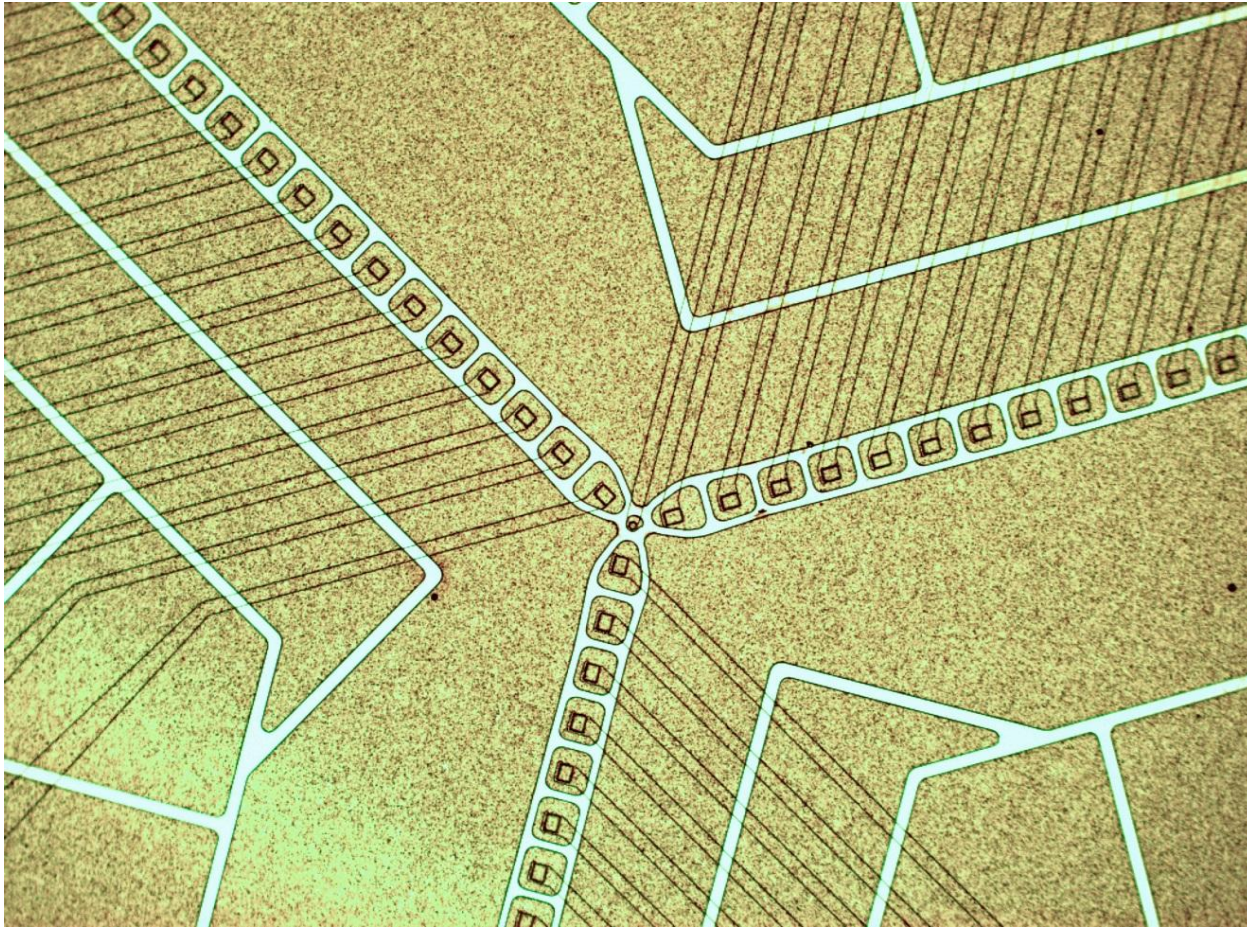
Simulated trap parameters:

- $V_{RF} = 190 \text{ V}$
- $\Omega/2\pi = 13.6 \text{ MHz}$
- Trap depth = 0.1 eV
- $\omega_{r/z}/2\pi = 720 \text{ kHz}$
- $\omega_c/2\pi = 210 \text{ kHz}$



Advanced Microfabricated Ion Traps

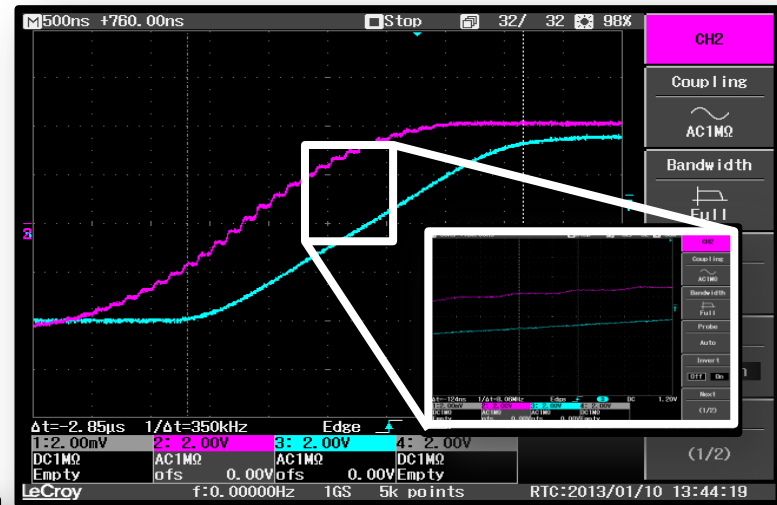
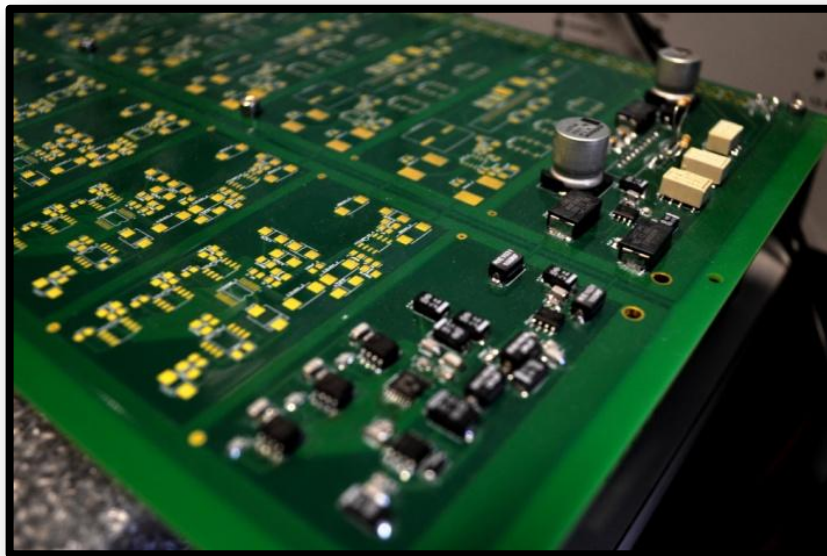
▶ Y-Junction with Centre Segmented Electrodes



Advanced Microfabricated Ion Traps

▶ Voltage Control System

- 16 bit accuracy and 16MSPS update rate
- 90 channels
- Adjustable voltage range of $\pm 100\text{V}$ and $\pm 10\text{V}$
- Low noise components and PCB design
- Digital, active and passive filters



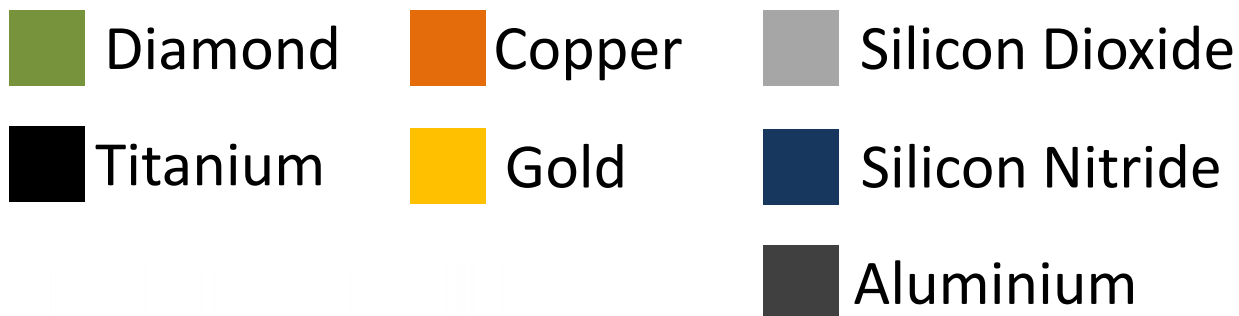
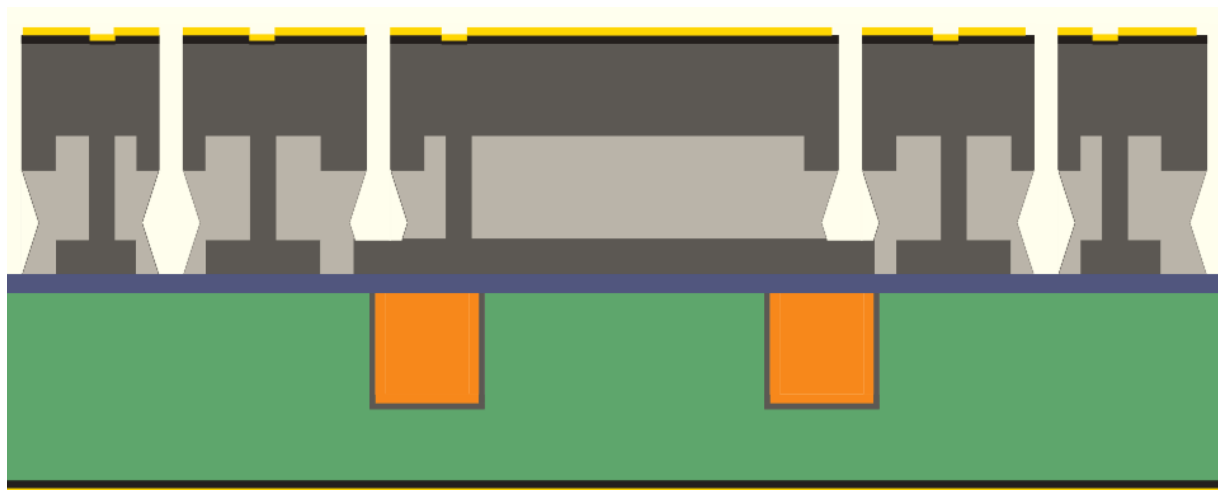
Test Signal with 8MSPS update rate
Pink: Output from DAC
Green: Signal after active filter

Ion Traps with B-Field Gradient Structures

- ▶ Novel Fabrication Process
- ▶ Current-Carrying Wire Structures
- ▶ Thermal Transport System
- ▶ Advanced Trap Designs
- ▶ Microfabrication Results

Ion Traps with B-Field Gradient Structures

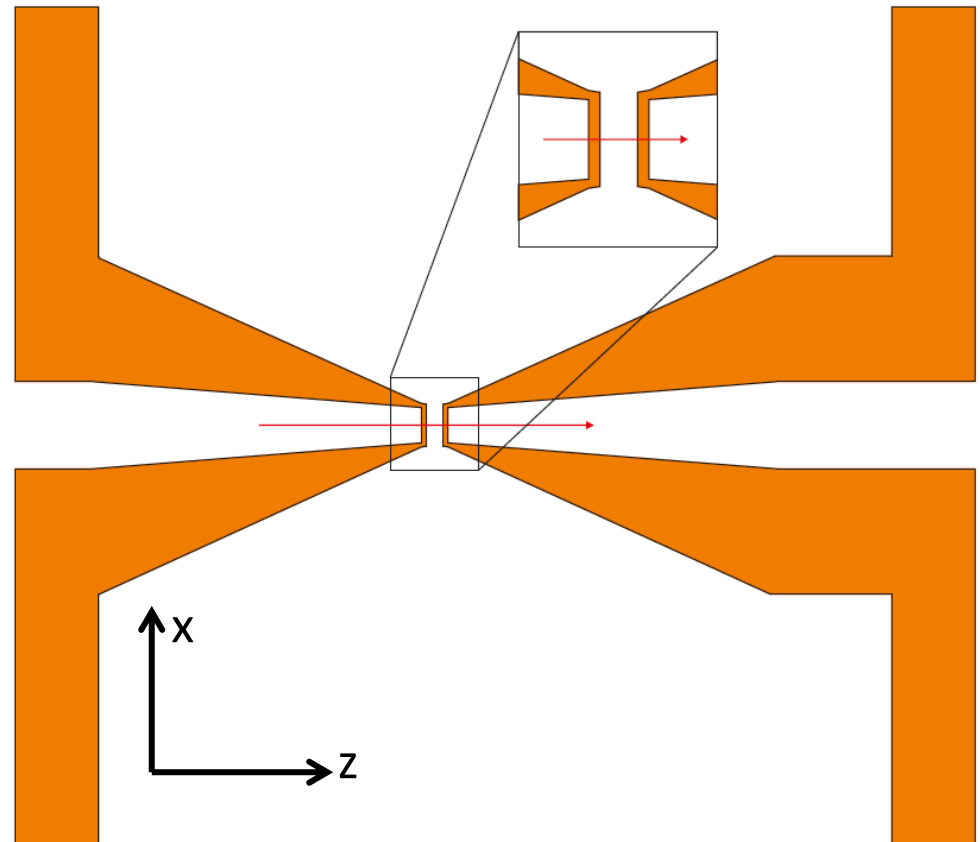
► Novel Fabrication Process



Ion Traps with B-Field Gradient Structures

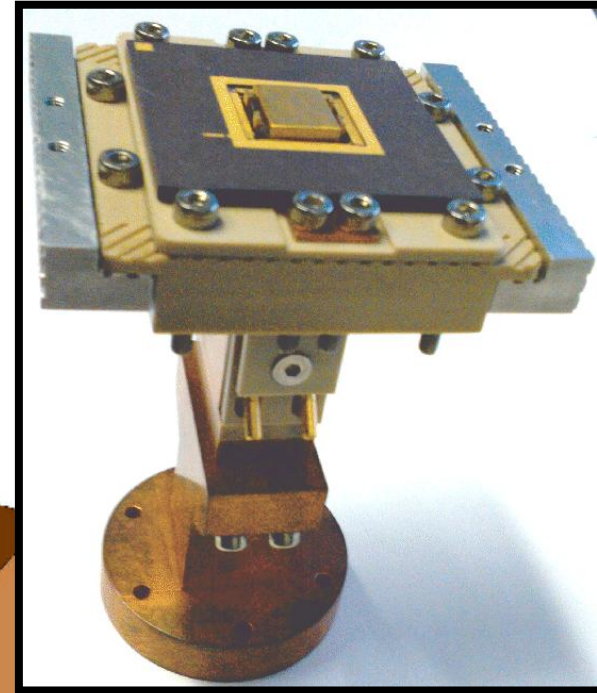
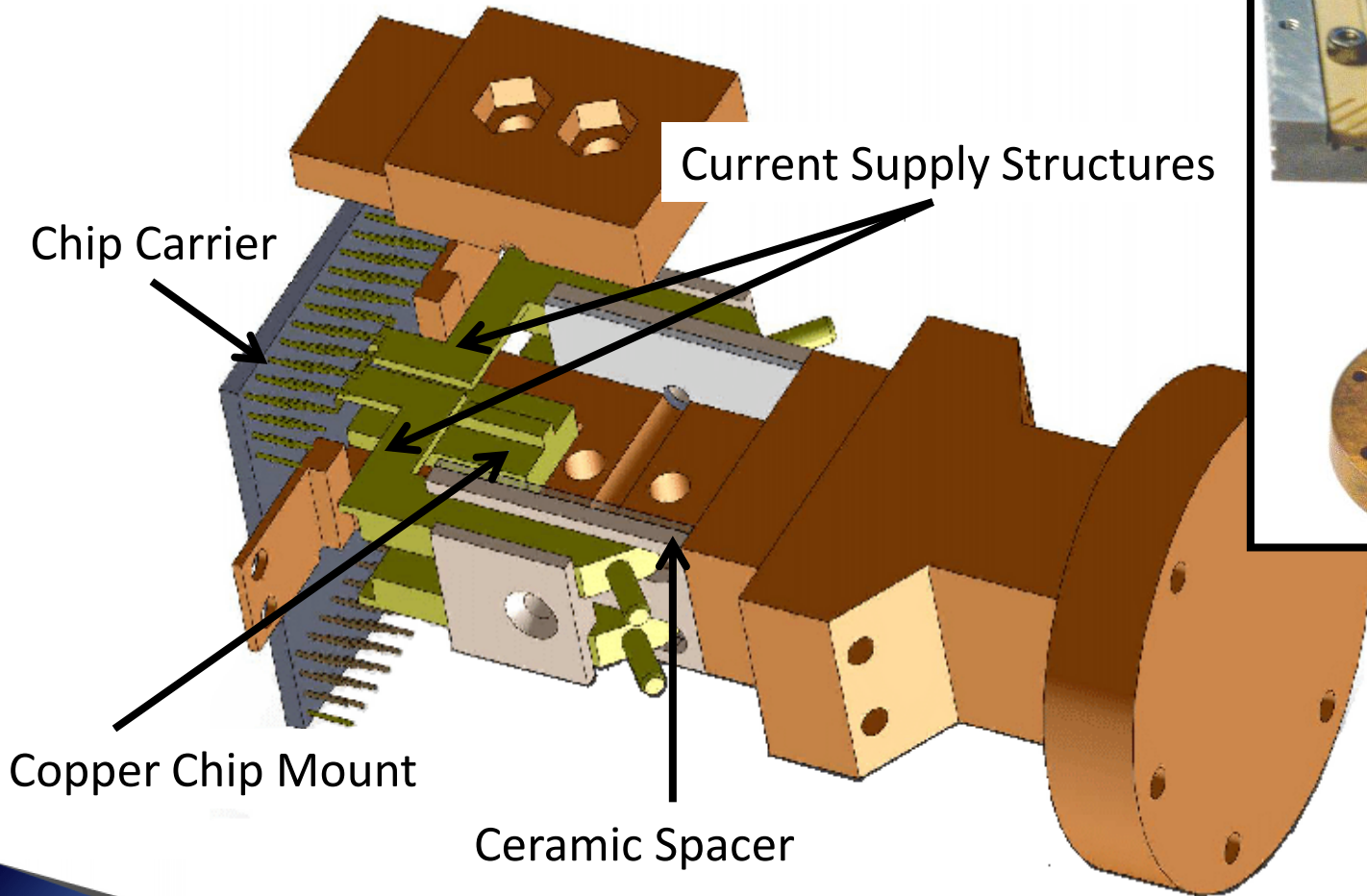
▶ Current-Carrying Wire Structures

- 30 μm thick and 40-1000 μm wide
- Embedded in diamond substrate
- Gradients $\sim 150\text{ T/m}$ for 12.5A at 60 μm ion height
- Traps with gradients along x and z direction are in production
- 5W of power dissipation



Ion Traps with B-Field Gradient Structures

► Thermal Transport System



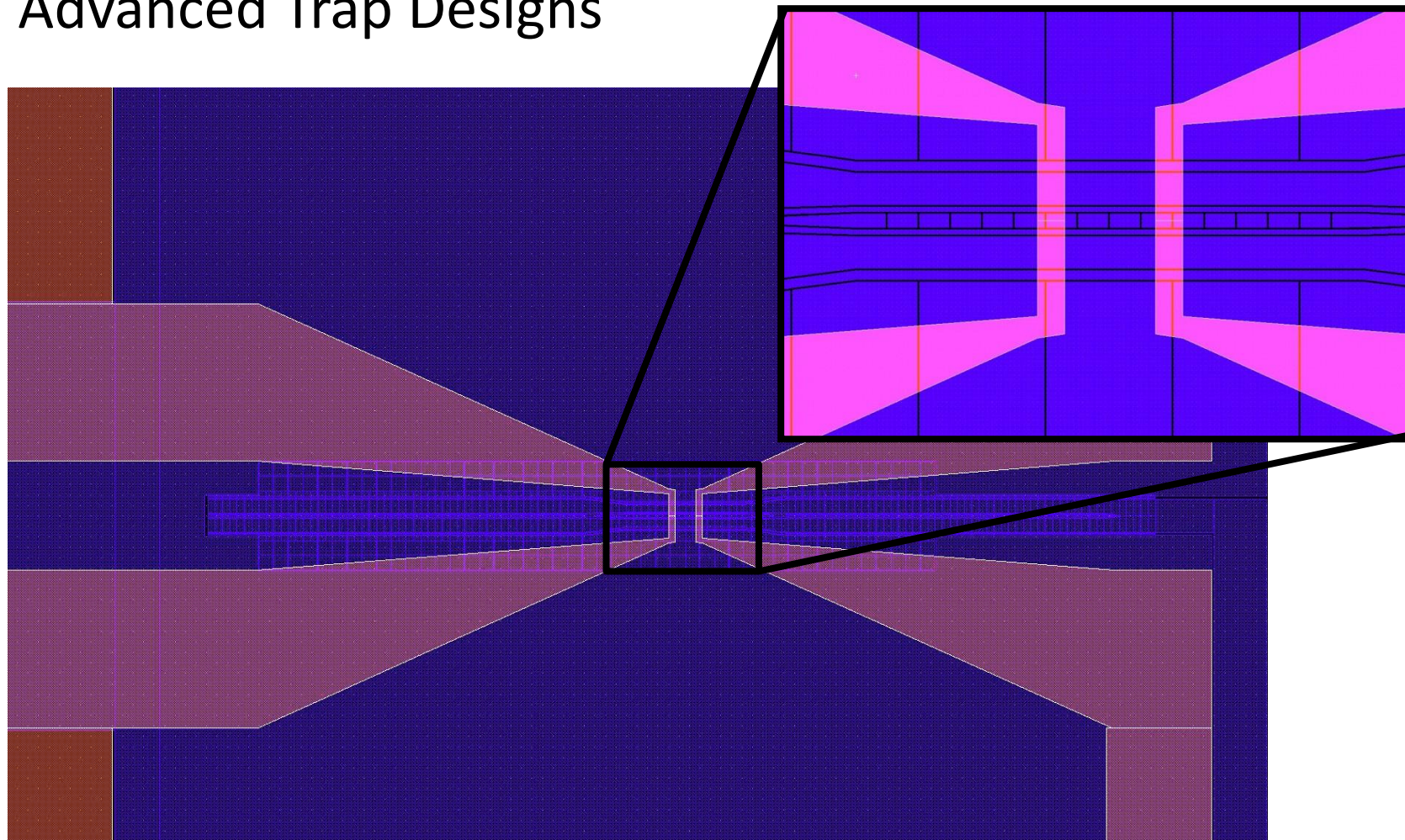
Ion Traps with B-Field Gradient Structures

► Advanced Trap Designs

Trap	Ion height (um)	Current – carrying wires	Special Features
Linear trap	60	yes	
	120	yes	Loading slot
	165	-	Detection slot
	250	-	Large number of control electrodes
X-junction	100	yes	
	200	-	Loading slot
Ring trap	35	yes	
	100	yes	
3 x 3 array	30	-	
	50	-	
	100	-	

Ion Traps with B-Field Gradient Structures

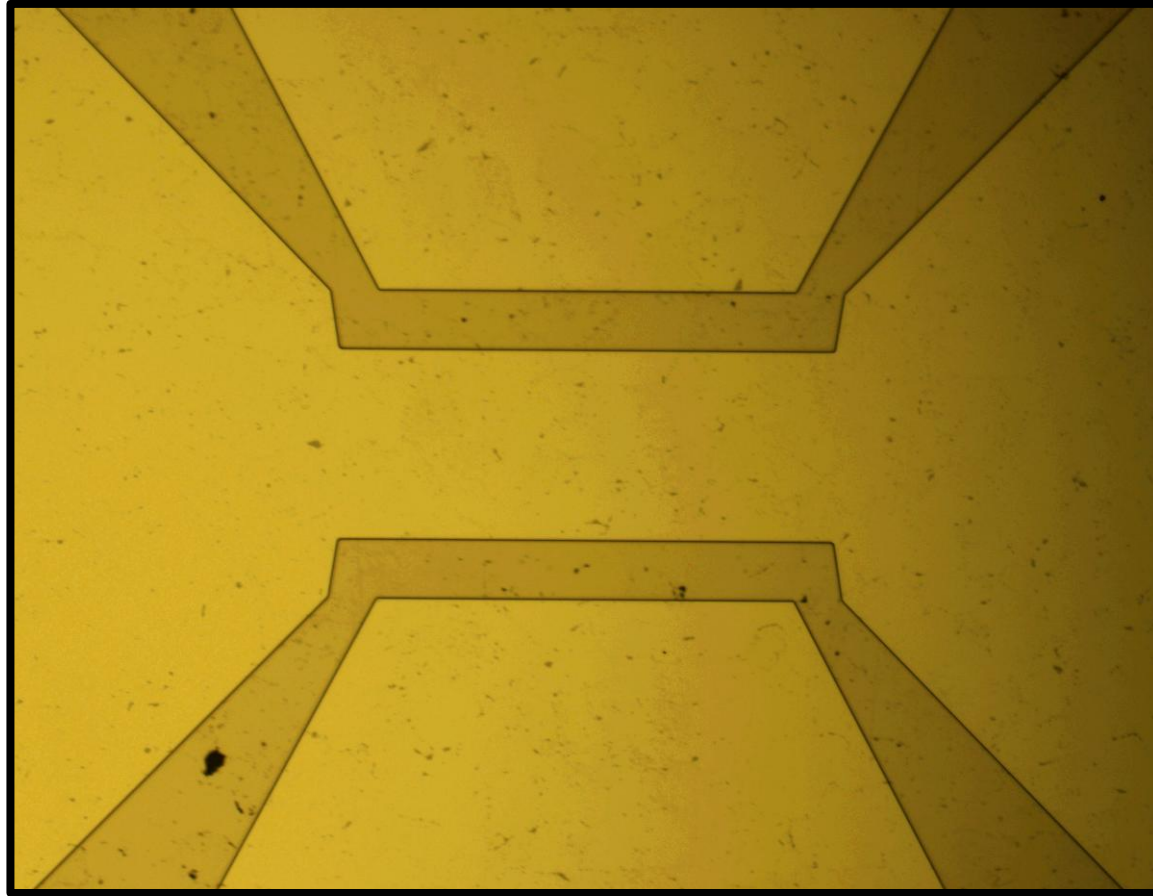
▶ Advanced Trap Designs



Linear trap design with current-carrying wires

Ion Traps with B-Field Gradient Structures

► Microfabrication Results



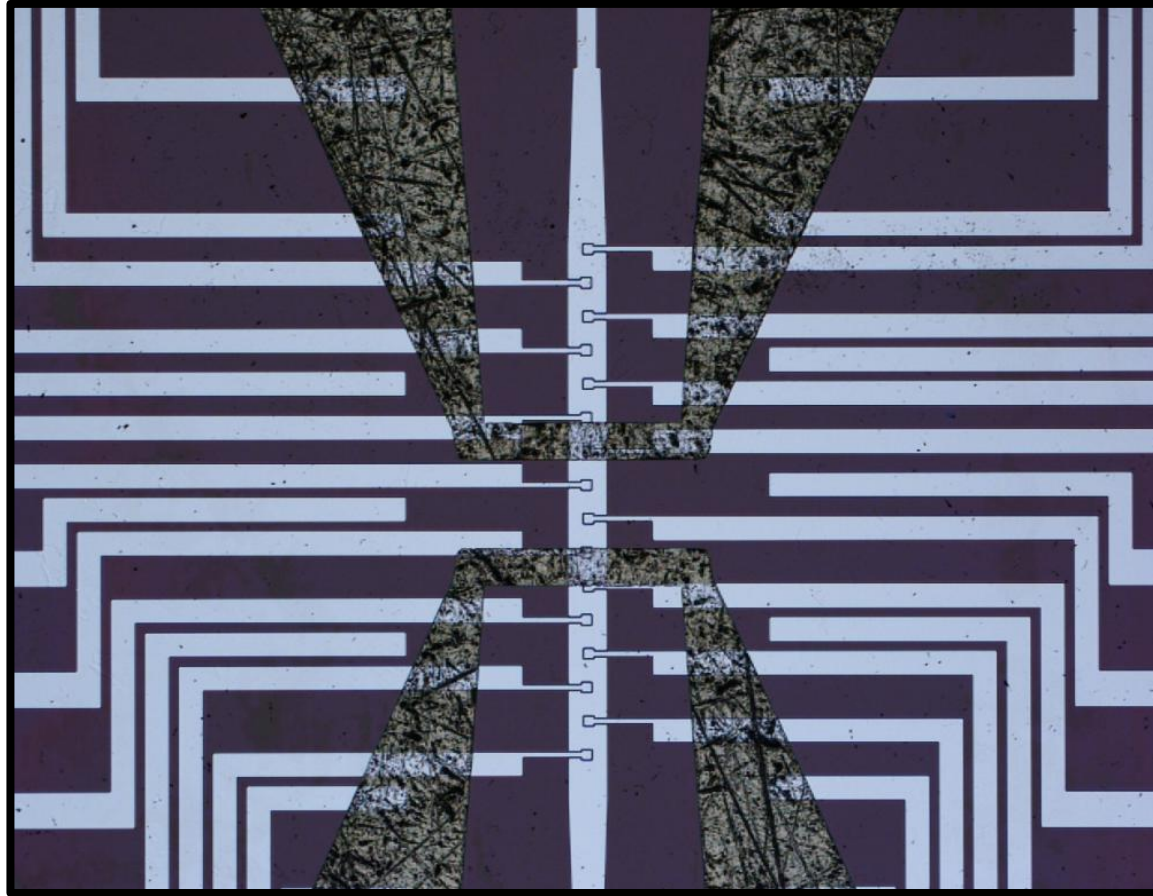
Ion Traps with B-Field Gradient Structures

► Microfabrication Results



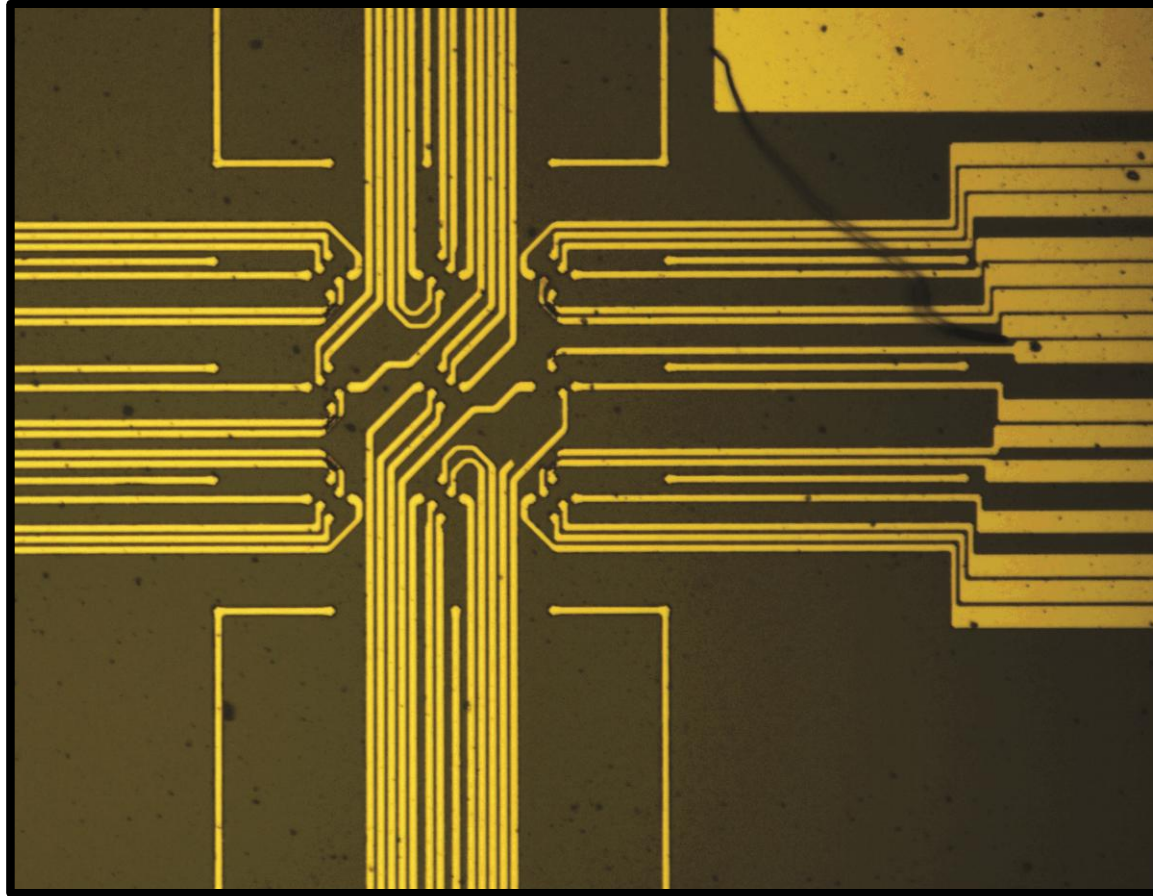
Ion Traps with B-Field Gradient Structures

► Microfabrication Results



Ion Traps with B-Field Gradient Structures

► Microfabrication Results



Cryogenic Ion Trapping

- ▶ Cryogenic Vacuum System
- ▶ Ion Chip Mount with Permanent Magnets
- ▶ Ion Trap with Integrated Niobium Nitride
High-Q Resonator
- ▶ Flat Multipole Ion Trap

Cryogenic Ion Trapping

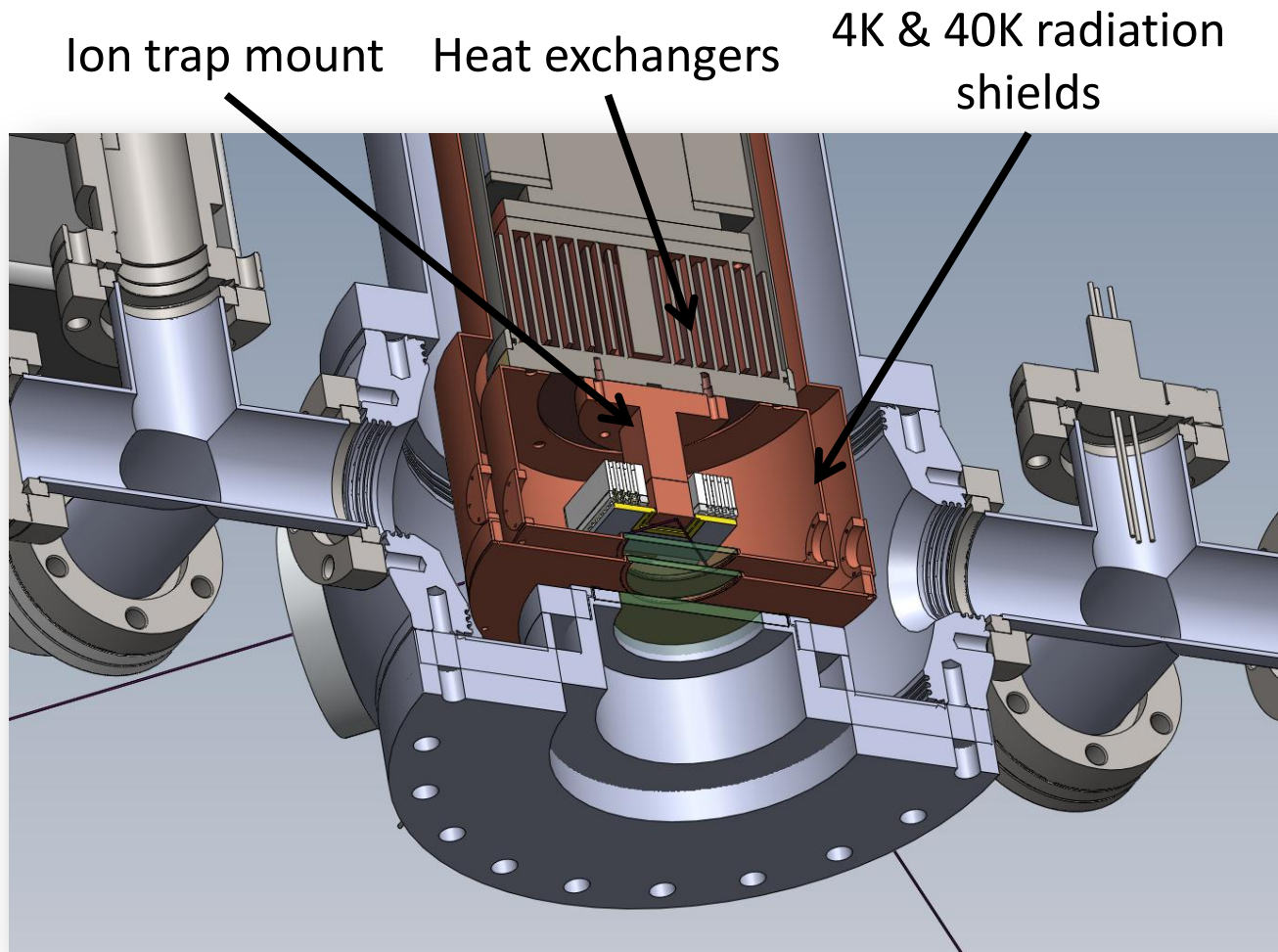
▶ Cryogenic Vacuum System

- Gifford-McMahon cryocooler
- Ultra low vibration interface $\sim 10\text{nm}$
- Helium exchange buffer gas



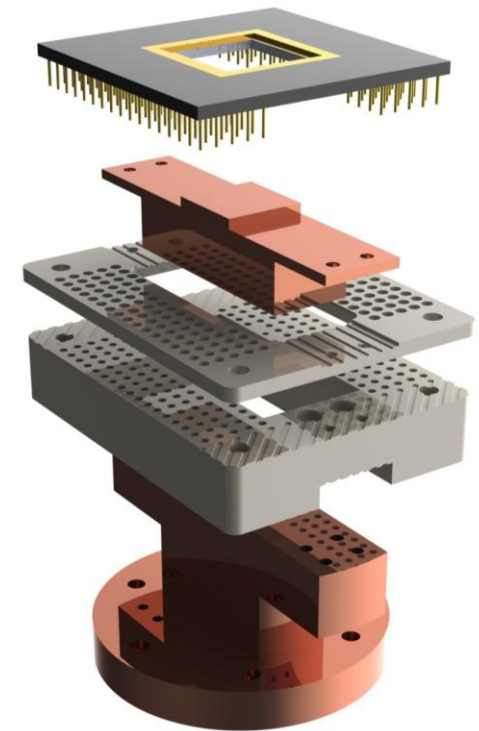
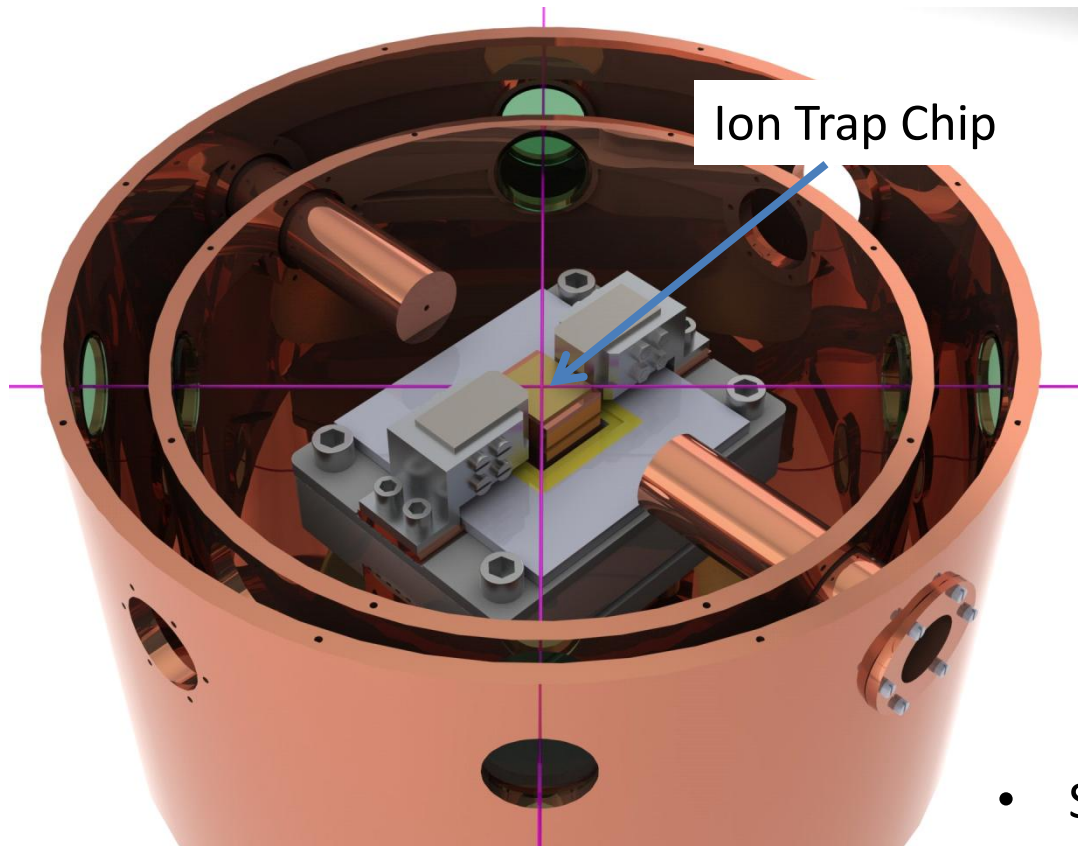
Cryogenic Ion Trapping

► Cryogenic Vacuum System



Cryogenic Ion Trapping

▶ Ion Chip Mount with Permanent Magnets



- Samarium Cobalt magnets
- Approximately 75 T/m gradient at the ions position

Cryogenic Ion Trapping

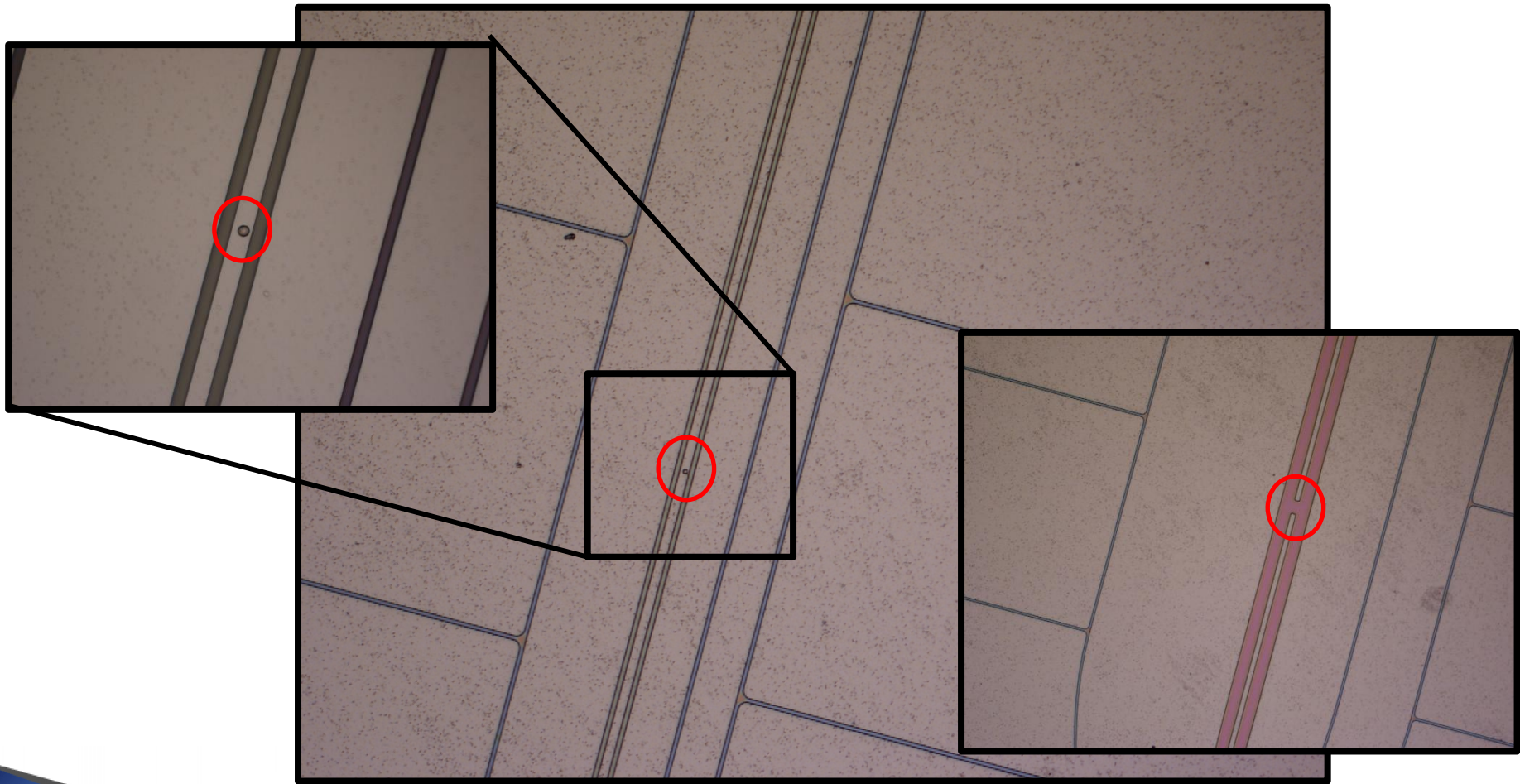
- ▶ Ion Trap with Integrated Niobium Nitride High-Q Resonator



 Sapphire  Niobium Nitride  Silicon Dioxide

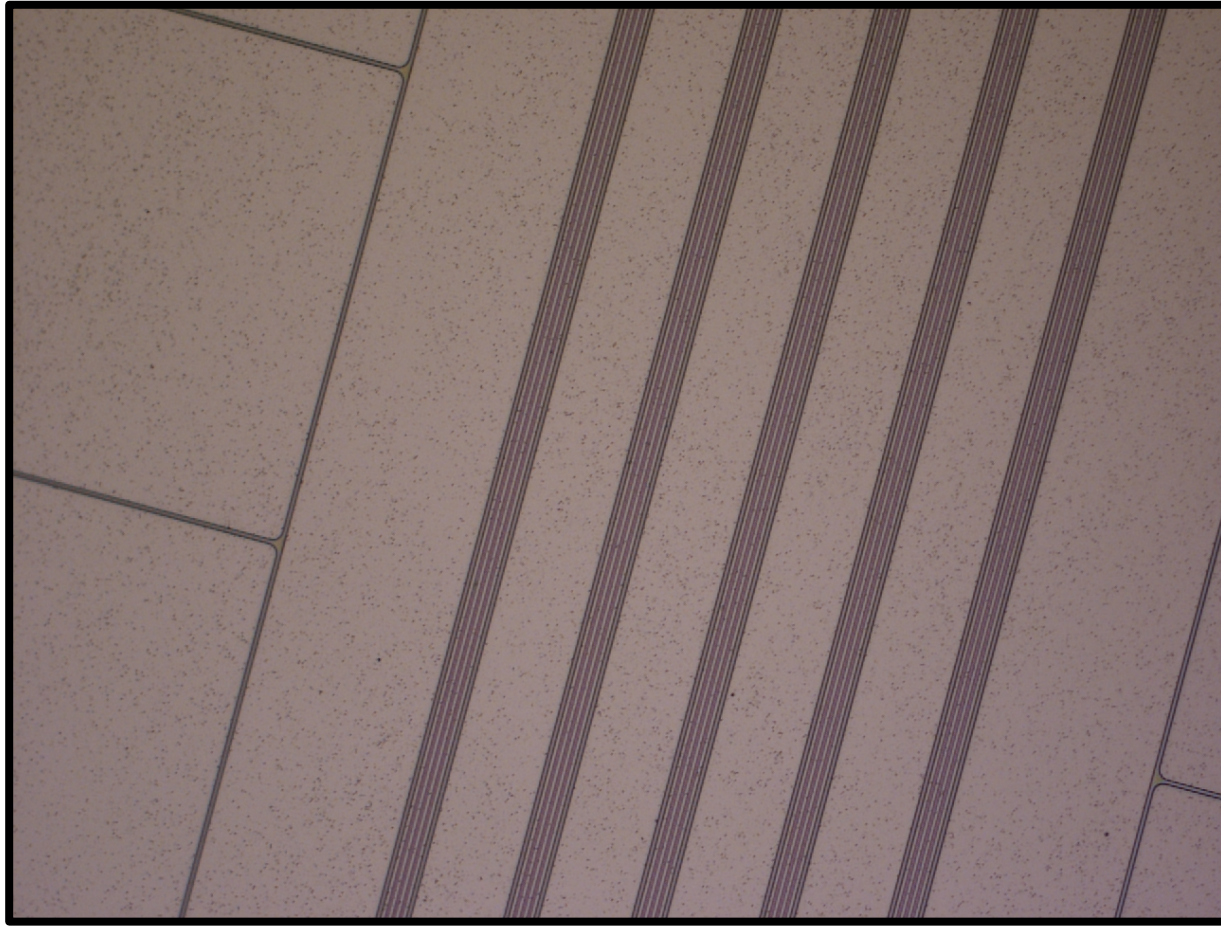
Cryogenic Ion Trapping

- ▶ Ion Trap with Integrated Niobium Nitride High-Q Resonator



Cryogenic Ion Trapping

▶ Flat Multipole Ion Trap



Summary

- ▶ Development of two-dimensional array and ring trap
- ▶ Variety of novel fabrication processes
- ▶ Advanced multilayered trap designs
- ▶ Cryogenic trapping and surface cleaning capabilities

The IQT Group

US
University of Sussex



Head of Group:

Dr. Winfried Hensinger

Postdocs:

Dr. Simon Webster

Dr. Gouri Giri

Research Assistants:

Dr. Marcus Hughes

Dr. James Siverns

PhD Students:

Bjoern Lekitsch

Seb Weidt

Kim Lake

Darren De Motte

Joe Randall

Eamon Standing

David Murgia

Tomas Navickas

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